## INFORMATION DISCLOSURE STATEMENT

Applicant

Mark W. Miles

App. No

09/413,222

Filed

: October 5, 1999

For

PHOTONIC MEMS AND

**STRUCTURES** 

Examiner

Hung X. Dang

Art Unit

2873

## CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

October 28, 2005

(Date)

Mark M. Abumeri, Reg. No. 43,458

## Mail Stop 313(c)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing (60) references to be considered by the Examiner. Also enclosed are (21) foreign patent references and/or non-patent literature as listed on the Information Disclosure Statement.

This Information Disclosure Statement is being filed within three months of the filing date, with an RCE or before receipt of a first office action after an RCE and no fee is required.

The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated:

Johnber 28, 2005 By:

Mark M. Abumeri

Registration No. 43,458

Attorney of Record Customer No. 20,995

(619) 235-8550

IDS 2032695 102705

PTO/SB/08 Equivalent

OCT 3 1 2005 IND RMATION DISCLOSURE TATEMENT BY APPLICANT

Application No. 09/413,222 Filing Date October 5, 1999 First Named Inventor Mark W. Miles 2873 Art Unit Examiner Hung X. Dang IRDM.056CP

(Multiple sheets used when necessary) SHEET 1 OF 3

**U.S. PATENT DOCUMENTS** Pages, Columns, Lines Where **Document Number** Publication Date Examiner Cite Relevant Passages or Relevant Name of Patentee or Applicant Number - Kind Code (if known) MM-DD-YYYY Initials No. Example: 1,234,567 B1 Figures Appear 01-20-1998 1 5,710,656 Goossen 2 12-30-1997 Brinkman et al. 5,703,710 06-03-1997 Arney et al. 3 5,636,052 Li et al. 4 5,619,059 04-08-1997 Moret et al. 5 5,579,149 11-16-1996 6 5,500,761 03-19-1996 Goossen et al. 7 03-19-1996 Mott 5,500,635 03-05-1996 Doherty et al. 8 5,497,172 Bloom 9 5,459,610 10-17-1995 5,401,983 03-28-1995 Jokerst 10 01-10-1995 Sharp et al. 11 5,381,253 05-10-1994 Bloom 12 5,311,360 Bozler et al. 5,233,459 08-03-1993 13 07-27-1993 Magel et al. 14 5,231,532 12-01-1992 Nelson 15 5,168,406 Link et al. 5,153,771 10-06-1992 16 17 5,124,834 06-23-1992 Cusano et al. Schildkraut et al. 12-24-1991 18 5,075,796 19 5,044,736 09-03-1991 Jaskie et al. 06-11-1991 Zahowski et al. 20 5,022,745 4,982,184 01-01-1991 Kirkwood 21 12-13-1988 Apsley 22 4,790,635 05-31-1988 Taylor 23 4,748,366 07-21-1987 TeVelde et al. 4,681,403 24 05-05-1987 Marks 4,663,083 25 Sadones 07-23-1985 26 4,531,126 TeVelde 05-28-1985 4,519,676 27 04-24-1984 Marks 28 4,445,050 TeVelde 09-06-1983 4,403,248 29

Attorney Docket No.

Examiner Signature

**Date Considered** 

\*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

T<sup>1</sup> - Place a check mark in this area when an English language Translation is attached.

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SHEET 3 OF 3

Application No.	09/413,222
Filing Date	October 5, 1999
First Named Inventor	Mark W. Miles
Art Unit	2873
Examiner	Hung X. Dang
Attorney Docket No.	IRDM.056CP

		NON PATENT LITERATURE DOCUMENTS		
Examiner Citor No		Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
	49	Jerman et al., "A Miniature Fabry-Perot Interferometer with a Corruggated Silicon Diaphragm Support," Sensors and Actuators A, Vol. 29, pp. 151, 1991.		
	50	Johnson, "Optical Scanners," Microwave Scanning Antennas, Vol. 1, 1964, pp. 251-261.		
	51	"Light Over Matter," June 1993. Circle No. 36.		
	52	Miles, Mark W., "A New Reflective FPD Technology Using Interferometric Modulation," Society for Information Display, 1997 Digest, Session 7.3.	,	
	53	Newsbreaks. "Quantum-trench Devices Might Operate at Terahertz Frequencies," Laser Focus World, May 1993.		
	54	Oliner, "Radiating Elements and Mutual Coupling," Microwave Scanning Antennas, Vol. 2, p. 131 et seq.		
	55	Raley et al., "A Fabry-Perot Microinterferometer for Visible Wavelengths," IEEE Solid-State Sensor and Actuator Workshop, June 1992, Hilton Head, SC.		
	56	Sperger et al., "High Performance Patterned All-Dielectric Interference Colour Filter for Display Applications," SID Digest 1994, pp. 81-83.		
	57	Stone, "Radiation and Optics, An Introduction to the Classical Theory," McGraw-Hill, pp. 340-343.		
	58	Walker et al., "Electron-beam-tunable Interference Filter Special Light Modulator," Optics Letter Vol. 13, No. 5, pp. 345-347, 1988.	-	
	59	Winton, John M., "A novel way to capture solar energy," Chemical Week, May 15, 1985, pp. 17-18.		
	60	Wu, "Design of a Reflective Color LCD Using Optical Interference Reflectors," ASIA Display 1995, October 16, 1995, pp. 929-931.		

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SHEET 2 OF 3

	1 TO/SB/00 Equivaler
Application No.	09/413,222
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Examiner	Hung X. Dang
Attorney Docket No	IRDM.056CP

			U.S. PATENT	DOCUMENTS	
Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
	30	4,389,096	06-21-1983	Hori et al.	
	31	4,377,324	03-22-1983	Durand et al.	
	32	4,228,437	10-14-1980	Shelton	
	33	4,099,854	07-11-1978	Decker et al.	
	34	3,955,880	05-11-1976	Lierke	
	35	3,813,265	05-28-1974	Marks	
	36	3,653,741	04-04-1972	Marks	
	37	3,443,854	05-13-1969	Weiss	
	38	3,439,973	04-22-1969	Paul et al.	
	39	2,534,846	12-19-1950	Ambrose et al.	

		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials	Cite No.	tom (hook magazina journal carial cymnosium catalog Atc.) date nage(s) Volume-Issue	
	40	Akasaka, "Three-Dimensional IC Trends," Proceedings of IEEE, Vol. 74, No. 12, December 1986, pp. 1703-1714.	•
	41	Aratani, et al., "Process and Design Considerations for Surface Micromachined Beams for a Tuneable Interferometer Array in Silicon," IEEE Micro. Workshop, Fort Lauderdale, FL, February 7-10, 1993, pp. 230-235.	•
	42	Aratani, et al., "Surface micromachined tuneable interferometer array," Sensors and Actuators A 43, 1994, pp. 17-23.	
	43	Conner, "P-36: Hybrid Color Display Using Optical Interference Filter Array," SID Digest 1993, pp. 577-580.	
	44	Goossen, et al., "Possible Display Applications of the Silicon Mechanical Anti-Reflection Switch," Society Information Display, 1994.	•
	45	Goossen, et al., "Silicon Modulator Based on Mechanically-Active Anti-Reflection Layer with 1Mbit/sec Capability for Fiber-in-the-Loop Applications," IEEE Photonics Technology Letters 6, September 1994, No. 9.	
	46	Gosch, "West Germany Graps the Lead in X-Ray Lithography," Electronics, February 5, 1987, pp.78-80.	
	47	Howard, "Nanometer-Scale Fabrication Techniques," VLSI Electronics: Microstructure Science, Vol. 5, 1982, pp. 145-153 and pp.166-173.	,
	48	Jackson, "Classical Electrodynamics," John Wiley & Sons Inc., pp. 568-573.	;

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